

IN THE UNITED STATES PATENT AND TRADEMARK

Wayne G. Renken

RECEIVED

Title:

Process Condition Sensing Wafer and Data Analysis System

JUL 20 2004

Application No.:

10/056,906

Filing Date:

January 24, 2002

Examiner:

Charles D. Garber

Group Art Unit:

2856

TECH CENTER 2800

Docket No.:

SENS.005US0

Conf. No.:

2359

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I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on May 12,

Franklin Dyer

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

AMENDMENT

Sir:

This is in response to the Office Action dated January 12, 2004, setting a period for response expiring on April 12, 2004. A Petition for Extension of Time requesting a one-month extension is herewith enclosed to extend the period for response until May 12, 2004.

No drawing amendments are being made.

Claim Amendments begin on page 2.

Remarks begin on page 8.

No specification amendments are being made.

Attorney Docket No.: SENS.005US0

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